EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S149	44	(semiconductor with (wafer or substrate) with (test$3 or prob$3)) with (((ion milling) or (sputter$3 with etch$3))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2010/03/03 10:46
S150	25	S149 and @ad<"20040225"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/03/03 10:47
S151	1701	(semiconductor with (wafer or substrate) with (test$3 or prob$3)) and (((ion milling) or (sputter$3 with etch$3))	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2010/03/03 10:56
S152	1087	S151 and @ad<"20040225"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2010/03/03 10:56
S153	0	S152 and (((ion milling) or (sputter etch$3)) with (prior or before) with (testing or probing or test or probe$1) with wafer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2010/03/03 10:59
S154	157	S152 and (((ion milling) or (sputter etch$3)) and (testing or probing or test or probe$1) with wafer)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2010/03/03 11:00

EAST Search History (Interference)

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3/3/2010 2:32:27 PM
C:\ Documents and Settings\ bau\ My Documents\ EAST\ Workspaces\ Metallization\ Electrical Contacts\ 10786807 bumps made of gold and its cleaning using ion milling before probing.wsp